

**EFFECT OF WO₃ DOPING CONCENTRATION ON THE PROPERTIES V₂O₅
THIN FILMS PREPARED BY VACUUM DEPOSITION TECHNIQUE**P. Yuvaraj¹, A. Priya¹, S. Pavithra¹, J. Jayachitra², N. Sivakumar^{1*}¹PG and Research Department of Physics, Chikkaiah Naicker College, Erode, Tamilnadu 638004, India.²Department of Physics, L.R.G government Arts College for Women, Tirupur, Tamilnadu 641604, India.

Abstract: Vanadium pentoxide (V₂O₅) is the promising material for energy storage applications. In the present work pure and WO₃ doped (2, 4, 6 and 8 wt. %) V₂O₅ thin films were prepared by vacuum deposition technique on ITO substrate. The structural behavior has been carried out by XRD and crystalline WO₃ doped vanadium pentoxide (V₂O₅) exhibits orthorhombic structure. The surface morphological images of the WO₃ doped V₂O₅ thin films shows granular surface which has been investigated by FESEM. Optical behavior indicates that the band gap decreasing (from 2.98 to 2.77 eV) with increasing doping concentration. Raman spectra were studied, in which several bands observed for these thin films have been explained on the basis of different bending, stretching band lattice phonon vibration modes occurring in the films. The electrochemical analysis results shows the WO₃ doped V₂O₅ exhibits the capacity of about 260 mAh/g after 100 cycles.

Keywords - vacuum deposition technique; vanadium pentoxide; structural, Optical and electrochemical properties

I. INTRODUCTION

Transition metal oxides are conventional special interest due to their higher stability as compared to organic electrochromism. In recent decades, vanadium oxides have been obtained a lot of attention, because of the enhancement of structural, optical, electronic and electrochemical properties which compared to other oxide materials. This type of vanadium oxides are suitable for different applications such as sensors [1], catalysis [2], capacitors [3], lithium ion batteries [4] and electrochromic devices [5]. In general, vanadium pentoxide (V₂O₅) is a non-stoichiometric material, which is known for its catalytic properties in oxidation reactions. It has been characterized by a semiconductor – to – metal transition occurring from a reversible change in the crystalline structure as a function of the temperature [6, 7]. Moreover, V₂O₅ is the most widely studied as a cathodic material presenting high capacity upon the reversible intercalation/deintercalation of Li⁺ due to its layered structure [8] and its high valence state [9]. Day and Sullivan [10] were studied and filed the first report related to the V₂O₅ can be used as a cathode material. The optical properties of vanadium dioxide are analyzed by a sharp decrease in optical transmission in the infrared spectrum during the semiconductor – metal transition. Due to this inconsistent behavior, vanadium dioxide has been presented as an attractive thin film material for electrical and optical switches and solar energy control for windows. Vanadium can be adopt a single valance in oxidation states from V²⁺ to V⁵⁺ in the form of VO [11], V₂O₃[12], VO₂[13], and V₂O₅[14]. The nanostructured of V₂O₅ is characterized by a large electrochemical surface area and good inter-connectivity for electric conductivity. Though, the lithiation processes in V₂O₅ bulk are relatively slow due to the low electric conductivity (10⁻³ to 10⁻² S.m⁻¹) and low Li⁺ diffusion coefficients (10⁻³ to 10⁻¹² cm².s⁻¹) [15,16].

In order to improve the electric conductivity and electrochromic properties, the binary combinations of oxides have been investigated. Promising effects on the host electrochromic materials are increased the efficiency, improved stability, a larger switching potential range or faster reaction kinetics. Granqvist [17] has reviewed the mixed metal oxides and reported valuable summary. In previous investigations on V₂O₅ added with metal oxide (MO₃) have showed the enhancement over the basic electrochromic properties of V₂O₅. Among those transition metal oxides, tungsten trioxide (WO₃) has wide band gap in the range of E_g = 2.5 – 2.8 eV at room temperature and appears to be the best electrochromic compound [18]. Tungsten has shown the most effective dopant ion in reducing the metal-semiconductor transition of vanadium oxide with lower T_c of 25 °C which as reported by Blackman et al [19]. Also, vanadium and tungsten oxides are important due to their current and substantial technological applications, in which tungsten has the similar ionic radius with V₂O₅ in the highest oxidation state [20].

Composite WO₃ added with MO_x films have been prepared by different methods such as sol-gel deposition [21], sputtering [22], electron-beam evaporation [23], and vacuum evaporation [24], etc. Moreover, Li et al [25] have reported W doped V₂O₅ nanotubes which have been prepared by self-assembling process. The novel tungsten-doped vanadium oxide xerogel films were prepared by the sol-gel and hydrothermal route for electrochromic electrodes [26].

In our present work, we have selected a vacuum deposition technique for preparing pure and WO₃ doped V₂O₅ thin films on ITO substrate. The effect of WO₃ doped V₂O₅ with different weight percentage (2, 4, 6 and 8 wt. %) has been systematically studied. Furthermore, the structural, surface morphological, optical and electrochemical properties of pure and WO₃ doped V₂O₅ thin films were investigated.

II. EXPERIMENTAL DETAILS

V_2O_5 and WO_3 powders (99.999% - sigma aldrich) were taken in different weight percentage (2, 4, 6 and 8 wt. %) and grinded for 3 hours with the help of mortar and sintered at $400^\circ C$ for 5 hour. The dimensions of substrates were 1.5 cm x 9 cm x 0.1 cm and these substrates were cleaned before deposition with acetone followed by isopropyl alcohol and rinsed in deionized water. The thermal evaporation technique (HHV 12" Vacuum coating unit Model 12A4D) was used to deposit pure V_2O_5 and WO_3 doped V_2O_5 thin films of thickness 100 nm on ITO coated glass substrates at $300^\circ C$ temperature under high vacuum (5.5×10^{-5} Torr). The distance between source and substrate was about 180 mm and a tantalum boat was used inside the vacuum chamber. The thickness of the films and evaporation/deposition rate were examined by quartz crystal monitor which was placed just below the substrate holder.

III. RESULTS AND DISCUSSION

A. XRD analysis

The structural properties of pure V_2O_5 and WO_3 doped V_2O_5 thin films were investigated by XRD measurements. Figure 1 shows, the XRD patterns which are indexed to orthorhombic V_2O_5 phase (JCPDS 41-1426) having lattice parameters $a = 11.516 \text{ \AA}$, $b = 3.56 \text{ \AA}$ and $c = 4.37 \text{ \AA}$. The diffraction peak at 20.275° is indicating the crystalline of V_2O_5 phase with the space group $C2/c$. The d-spacing values of all diffraction peaks are identical to those of the orthorhombic crystalline phase V_2O_5 (Space Group: $Pmnm$). Previous reports are available for V_2O_5 with the same phase [27].

As the doping concentration increases, the intensity of the preferred orientation of (0 0 1) indicates that the decreased crystallinity. In the present XRD result, (0 0 1) plane has the highest intensity for pure V_2O_5 which is similar to previous literature report [28]. Ashvani kumar et al [29] have observed that the high substrate temperature leads to higher oxygen vacancy in the V_2O_5 phase causing shift to lower valence state. The induced vacancy can go ahead to partial collapse of the V-O layer assisting the formation of V_2O_5 phase [30-31].

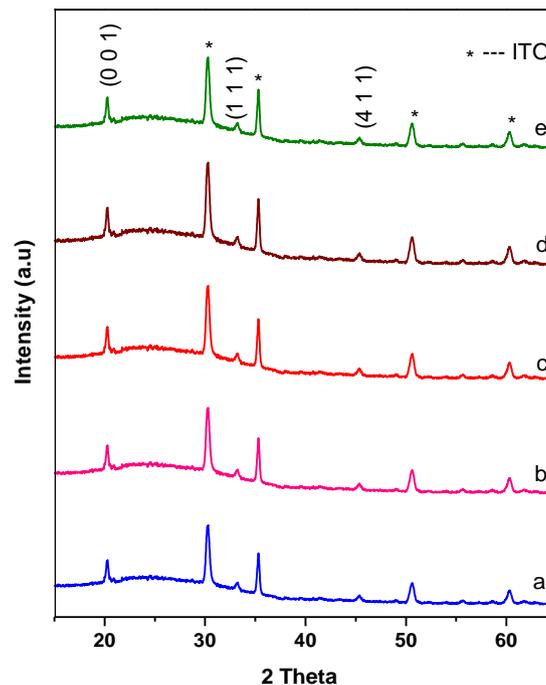


Fig.1. XRD patterns of pure V_2O_5 and WO_3 doped V_2O_5 thin films
(a) pure (b) 2 at % WO_3 (c) 4 at % WO_3 (d) 6 at % WO_3 (e) 8 at % WO_3

The increasing of WO_3 concentrations shows that the peaks are shifted (between the diffraction angles (2θ) of 20.275° and 20.484°). As the doping concentrations of WO_3 increase, no other peak is observed for WO_3 in the WO_3 doped V_2O_5 films using Vacuum deposition technique. The reasons are (i) the minimum amount of WO_3 concentration may present in the form of very small clusters in V_2O_5 lattices, therefore, it might be very complex to detect by XRD instrument and (ii) probably placed in the grain boundaries of the V_2O_5 nanocrystals - or distributed atomically within the V_2O_5 lattice (e.g. by occupying the central positions of the tetrahedral arrangement or by replacing some V atoms in their lattice position) [32-34].

TABLE.1. THE MICROSTRUCTURAL PROPERTIES OF THE PURE V₂O₅ AND WO₃ DOPED V₂O₅ THIN FILMS

Materials	Diffraction angle 2θ (deg)	Plane	Crystallite size (D) (nm)	Micro strain (ε) (x 10 ⁻³ lines ⁻² m ⁻⁴)	Dislocation density (x10 ¹⁴ cm ⁻²)	Stacking Fault (x 10 ⁻²)	Texture Coefficient (T _c)
V ₂ O ₅	20.275	0 0 1	42	0.822	0.193	5.589	1.01
2% WO ₃	20.381	0 0 1	37	0.943	0.419	7.265	0.89
4% WO ₃	20.484	0 0 1	34	1.102	0.301	8.450	0.87
6% WO ₃	20.478	0 0 1	28	1.234	0.693	12.140	0.92
8% WO ₃	20.372	0 0 1	24	1.407	0.806	16.935	1.06

Table 1 shows the microstructural properties of pure V₂O₅ and WO₃ doped V₂O₅ thin films for the preferred orientation of (0 0 1) plane. The crystallite size (D) [35], microstrain (ε), dislocation density (δ), stacking fault (SF) and texture coefficient (T_c) values can be obtained [36].

The crystallite size (D) of the preferred orientation (0 0 1) plane is decreased from 42 to 24 nm for increasing the doping concentration of WO₃ from 0 to 8 wt. % as shown in Table 1. Microstrain, dislocation density and stacking fault have increased with increasing of doping concentration (Table 1). Madhavi et al. [37] observed that decreasing of crystallite size and increasing of strain by increasing of WO₃ doping concentration on V₂O₅. Lethy et al. [38] also reported that the microstructural investigation shows that incorporation of titanium strongly disturbs the WO₃ lattice and decreases the crystallite size.

B. Field Emission Surface Morphology studies

The surface structure and grain arrangement were analyzed by the FESEM results. Surface images of the pure V₂O₅ and WO₃ doped (4 and 8 wt. %) V₂O₅ samples are shown in figure 2. The image of pure V₂O₅ sample (Fig. 2a) shows that the surface appears to be spherical in shape with spongy bush like structure, also with different grain size and free of grain boundaries. Previous reports [39, 40] shown the similar morphology for V₂O₅ film sample deposited at 400 °C. By increasing WO₃ doped (4 and 8 wt. %) in V₂O₅ samples (Fig. 2b and 2c), shown that the shape of the grains change into the mixed cubical and monoclinic phases. From the FESEM images, the average particle size has been observed to be in the range of ~ 25 nm for pure V₂O₅ samples and for WO₃ doped (4 and 8 wt. %) samples ~21 nm and ~18 nm respectively. Therefore, it is evident that, from these FESEM images, the addition of WO₃ in V₂O₅ resulted in decrease in the average particle size

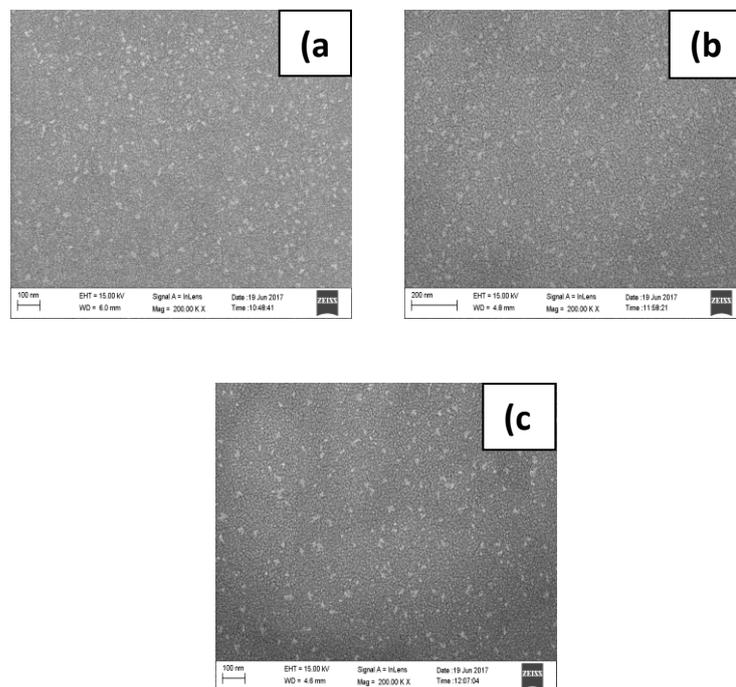


Fig.2. FESEM images of pure V₂O₅ and WO₃ doped V₂O₅ thin films, (a) pure (b) 4 at % WO₃ (c) 8 at % WO₃

C. Elemental Analysis

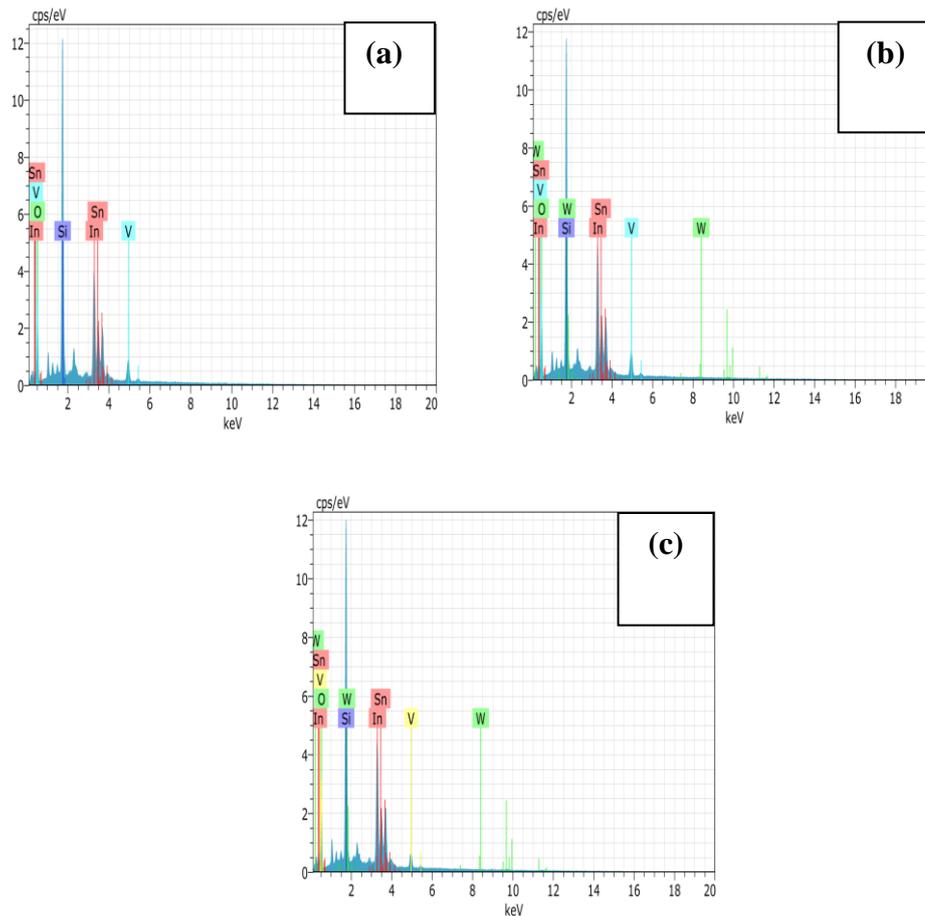


Fig.3 EDAX images of pure V_2O_5 and WO_3 doped V_2O_5 thin films
 (a) pure (b) 4 at % WO_3 (c) 8 at % WO_3

The stoichiometric ratio of the pure V_2O_5 and WO_3 doped V_2O_5 thin films were confirmed by the EDX spectra. The EDX spectra for WO_3 doped V_2O_5 thin films for different WO_3 doping concentration of 4 and 8 wt. % are shown in figure 3 (a-c). The EDX spectra reveal that the elements of W, V and O present in the prepared samples. As the doping concentration of W increases, the atomic percentage of W increases and O decreases in the present study. Table 2 represents that the atomic percentage of W and V increase and O decreases as increasing the doping concentration of W.

TABLE. 2 ATOMIC RATIO OF THE PURE V_2O_5 AND WO_3 DOPED V_2O_5 THIN FILMS

WO ₃ doping concentration (wt. %)	Atomic ratio (%)		
	W	V	O
0	-	30.67	69.33
4	2.13	30.83	67.04
8	3.95	29.93	66.12

D. Optical Properties

Figure 4 shows the optical absorption spectra of the pure V_2O_5 and WO_3 doped (2, 4, 6 and 8 wt. %) in the wavelength range of 300 to 900 nm. From the spectra, it has been clearly observed that the absorption edge shifted towards higher wavelengths with an increase in doped of WO_3 . The shift in absorption of the doped sample might be due to change in electronic structure and surface morphology (grain boundaries and roughness) of films. The essential absorption of V_2O_5 is due to the electronic transitions from occupied 2p bands of oxygen to unoccupied 3d bands of vanadium ($O_{2p} \rightarrow V_{3d}$) [41]. Figure 4 shows the absorption spectra of the pure and WO_3 doped V_2O_5 nanoparticles with the absorption peaks at 416, 425, 436, 443 and 448 nm respectively. The band gap energy of pure and WO_3 doped V_2O_5 thin

films has been calculated by using the relation $E_g = hc/\lambda$ and the calculated values 2.98, 2.92, 2.84, 2.80 and 2.77 eV are correspond to pure, 2, 4, 6 and 8 wt. % WO_3 doped V_2O_5 thin films respectively. The observed E_g value is in good agreement with the E_g value determined in literature [42]. From these values it is concluded that the band gap energy decreases with WO_3 doping, which shows a red shift in wavelength.

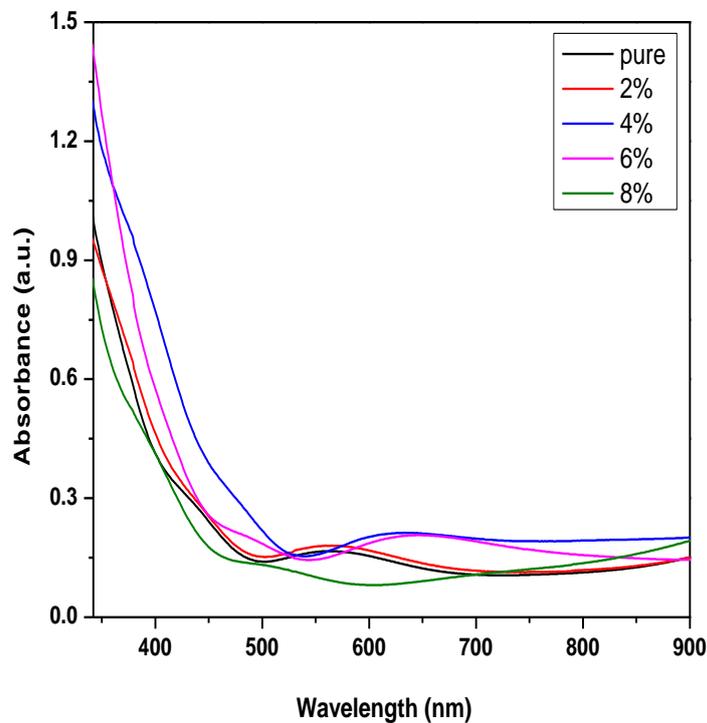


Fig.4. The Variation of % of Absorbance with Wavelength
(a) pure (b) 2 at % WO_3 (c) 4 at % WO_3 (d) 6 at % WO_3 (e) 8 at % WO_3

e. Raman Studies

In order to study the phase and local structure of metal oxide thin films, Raman studies were carried out for pure V_2O_5 and doped WO_3 samples. The change in the molecular polarizability associated with the vibrational mode of the molecule gives rise to the Raman shift and presents valuable information about the structural units and different vibrational modes. Figure 5 shows the Raman spectra of pure V_2O_5 and doped WO_3 thin films. The orthorhombic structure of V_2O_5 compound belongs to space group of $Pm\bar{m}n (D_{2h}^{13})$ with $Z=2$ [43]. Also, it consists of chains of edge sharing VO_5 square pyramids, and V, O_1 and O_2 atoms occupy $4f$ Wyckoff positions with site symmetry C_s . The 'V' atoms form five bonds with 'O' atoms. Normally the low frequency band in Raman spectra is attributed to lattice vibration of V_2O_5 [44]. Thus, the vibrational modes observed in the low frequency region are called external modes and the modes observed in the high frequency region are called internal modes. The internal modes include V-O stretching vibrations in the $500-1000\text{ cm}^{-1}$ region and V-O-V bending vibrations in the range $200-500\text{ cm}^{-1}$. The external vibrations, containing translation (T_x, T_y, T_z) and libration (R_x, R_y, R_z) modes viewed as relative motions of the structural units, lie in the low-frequency region.

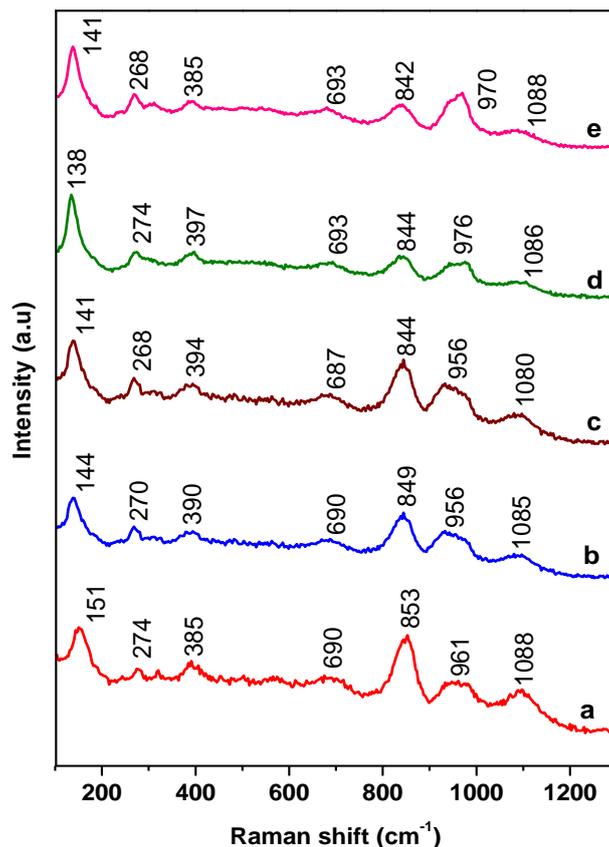


Fig. 5 Raman spectra of pure V_2O_5 and WO_3 doped V_2O_5 thin films
 (a) Pure (b) 2 at % WO_3 (c) 4 at % WO_3 (d) 6 at % WO_3 (e) 8 at % WO_3

In our present studies, a band at 1088 cm^{-1} has been assigned to stretching vibration mode of $V-O_1$ bond along O axis. The narrow peaks 961 cm^{-1} are attributed to the stretching mode related to the A_g symmetric vibrations of the shortest vanadium-oxygen bond (vanadyl $V=O$). The new peak observed at 853 cm^{-1} is because of oxygen deficiency [45]. The band showing at 690 cm^{-1} has been assigned to (V_2-O) stretching mode which results from corner shared oxygen common to two pyramids. Each V_2O_5 layer is built up from VO_5 square pyramids sharing edges and corners. The absence of two major bands at 520 cm^{-1} and 650 cm^{-1} confirms that V_4O bonds are not formed in this oxide film which as reported earlier [46]. The lattice vibration mode has appears very powerful at 151 cm^{-1} which indicates organization of long range order in mixed oxide film. The shifting of 1088 cm^{-1} band to 1080 cm^{-1} for the doped WO_3 in V_2O_5 (Fig. 5 c) which indicates lengthening of O-V-O bond.

F. Electrochemical Analysis

The electrochemical performance has been analyzed through cyclic voltametry and the CV curve of pure and WO_3 doped V_2O_5 on ITO substrate are shown in figure 6. The electrochemical analysis was carried out in an three electrode cell in which the coated substrate was taken as an working electrode, $AgCl$ as an reference electrode and platinum was taken as counter electrode. The theoretical specific capacity of V_2O_5 is about 273 mAh/g . After 100 cycles the pure V_2O_5 gives about 250 mAh/g with 80% of the capacity retention has been take place. But in WO_3 doped V_2O_5 has 90% of the capacity retention from its original value. It has been observed that the doping of WO_3 has increased the conductivity of the material causes easier movement ions during charging/discharging of the material which increases the cycling capacity and stability was also increased on doping of WO_3 .

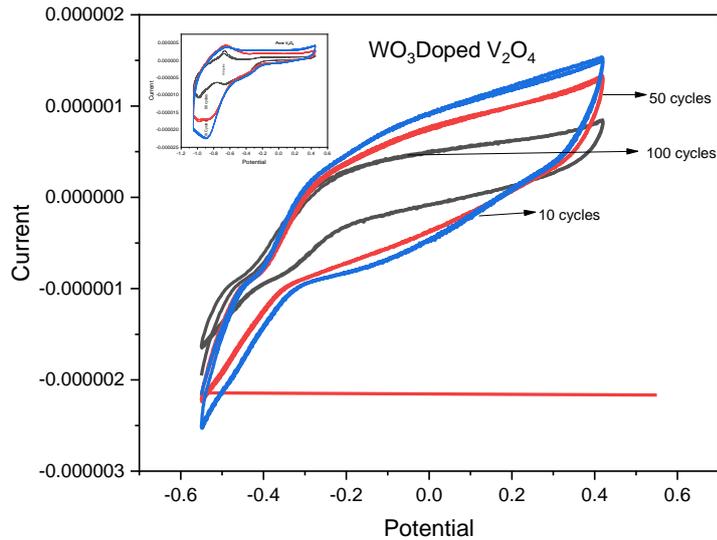


Fig.6. Potential and specific capacity of pure V_2O_5 and WO_3 doped V_2O_5 thin films
 (a) pure (b) 2 at % WO_3 (c) 4 at % WO_3 (d) 6 at % WO_3 (e) 8 at % WO_3

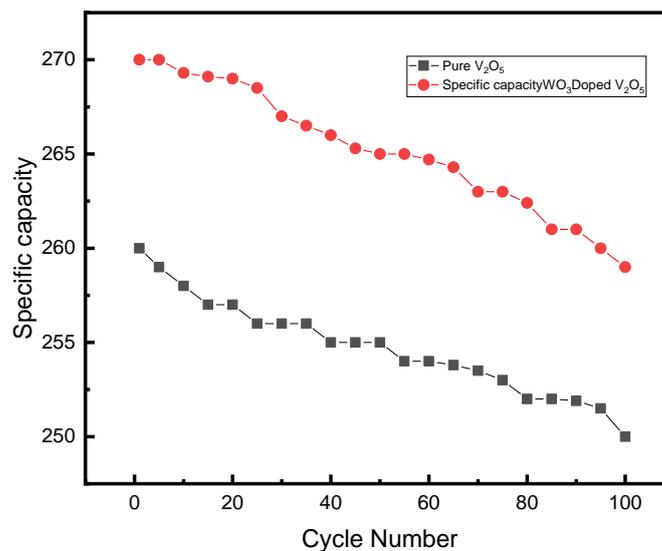


Fig.7. Specific capacity for varied cycle numbers for pure V_2O_5 and WO_3 doped V_2O_5 thin films
 (a) pure (b) 2 at % WO_3 (c) 4 at % WO_3 (d) 6 at % WO_3 (e) 8 at % WO_3

IV. CONCLUSION

Pure and WO_3 doped (2, 4, 6 and 8 wt. %) V_2O_5 thin films were prepared by the vacuum deposition technique on ITO substrate. The effect of WO_3 doping on the structural, morphological, compositional, optical and electrochromic properties of V_2O_5 thin films had been studied. It was observed that, Crystalline WO_3 doped vanadium pentoxide (V_2O_5) thin films with orthorhombic structure are found to have diffraction peaks correspond to (0 0 1), (1 1 1) and (4 1 1) crystal planes. The surface morphology has been carried out using FE-SEM, and from the image, the particle size was decreases on doping WO_3 . The elemental confirmation has been done by using EDAX for both pure and WO_3 doped V_2O_5 . From the UV result, the optical bandgap values of the films were in the range of 2.98 to 2.77 eV. The Raman studies indicates that, the shifting of 1088 cm^{-1} band to 1080 cm^{-1} for the doped WO_3 in V_2O_5 which represent the lengthening of O-V-O bond. Finally the electrochemical analysis results shows the WO_3 doped V_2O_5 gives the capacity of about 260 mAh/g after 100 cycles.

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